

Applicant: Ryo NAKAGAKI, et al.

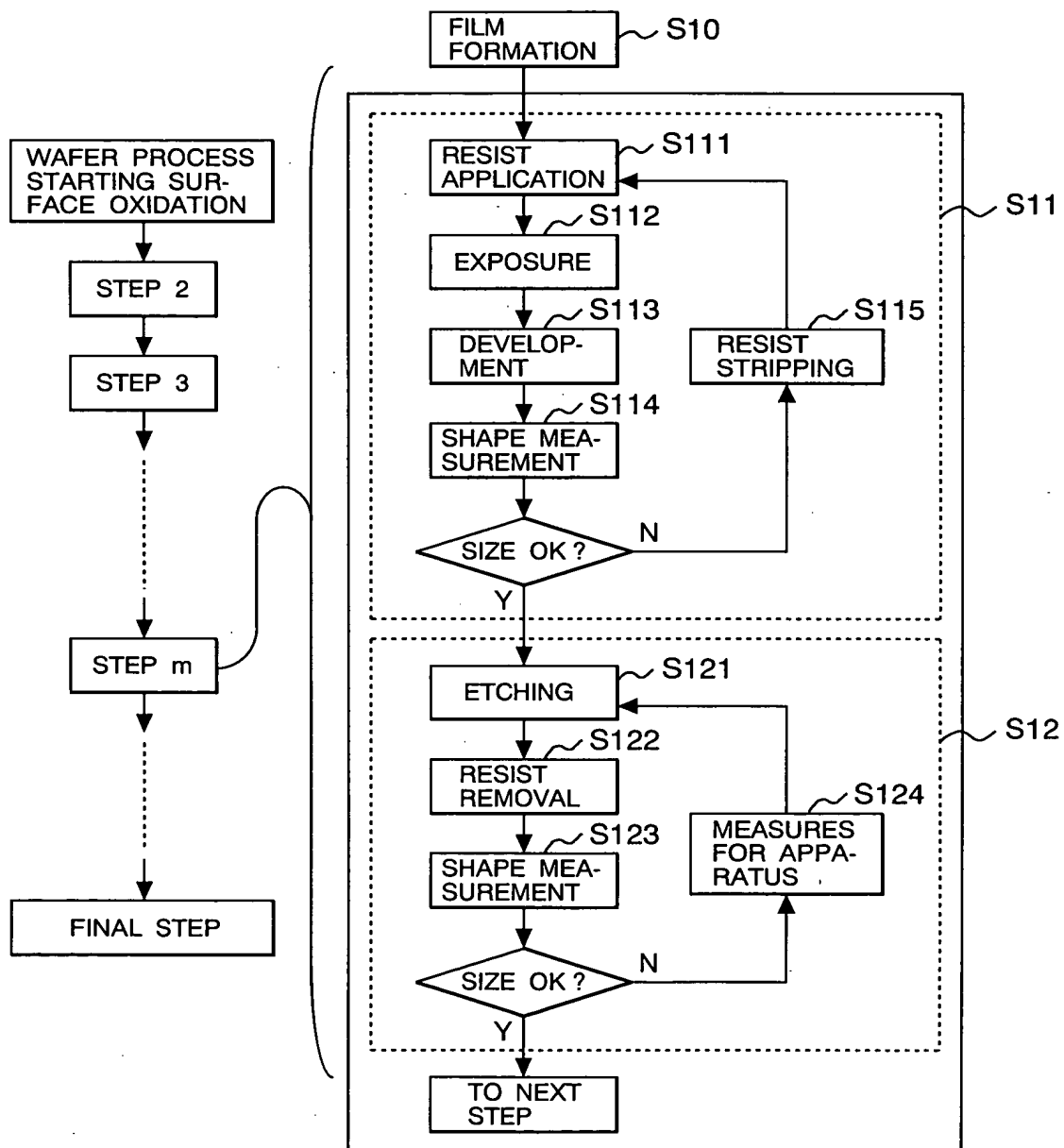
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FIG. 1



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FIG. 2A

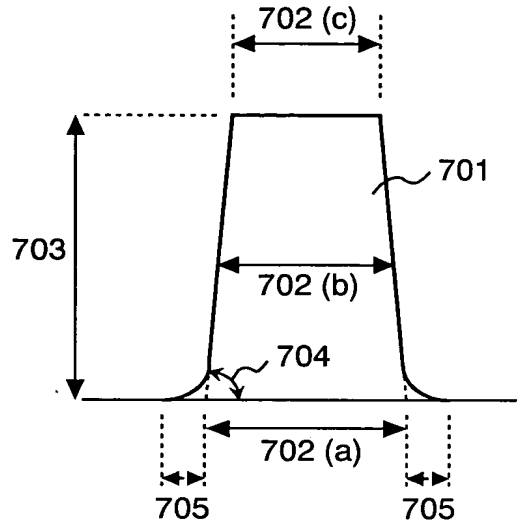
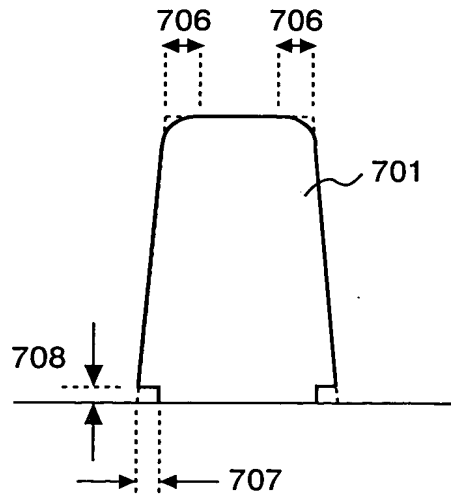


FIG. 2B



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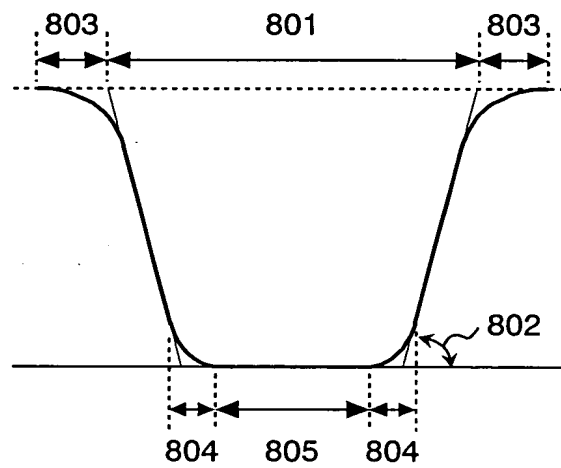
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**FIG. 3**



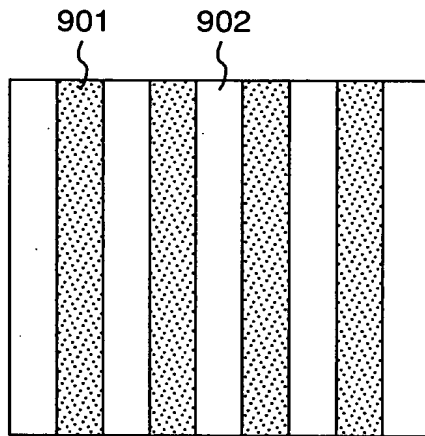
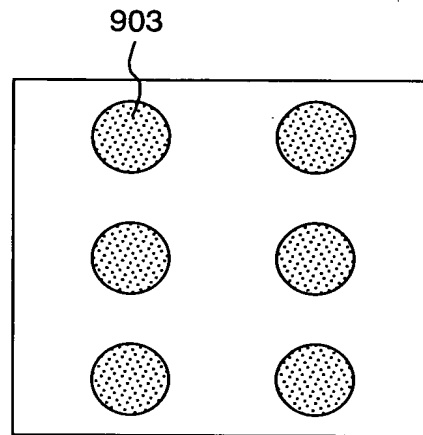
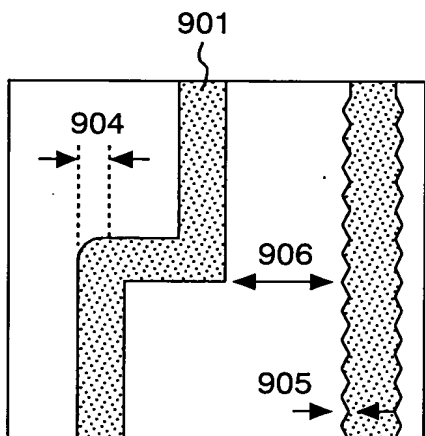
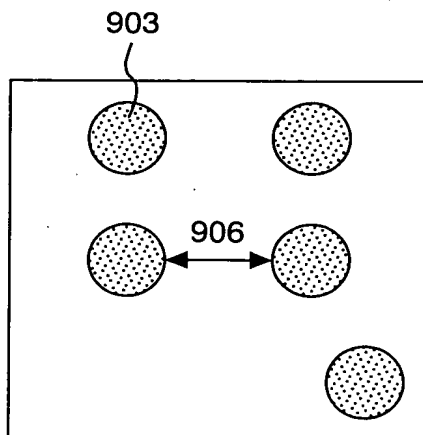
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**FIG. 4A****FIG. 4B****FIG. 4C****FIG. 4D**

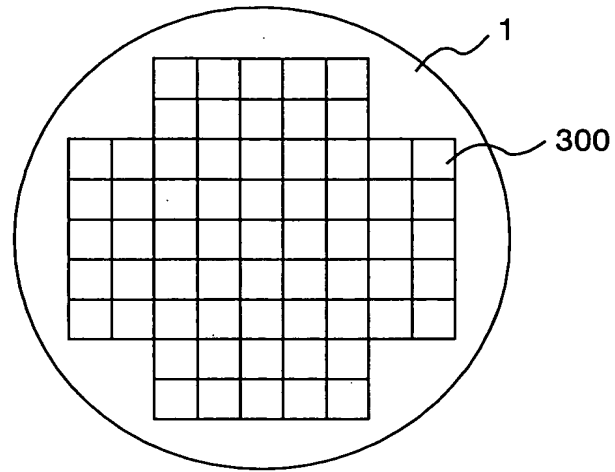
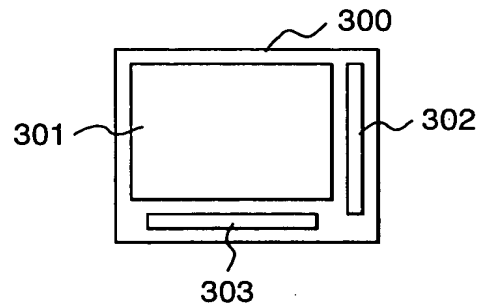
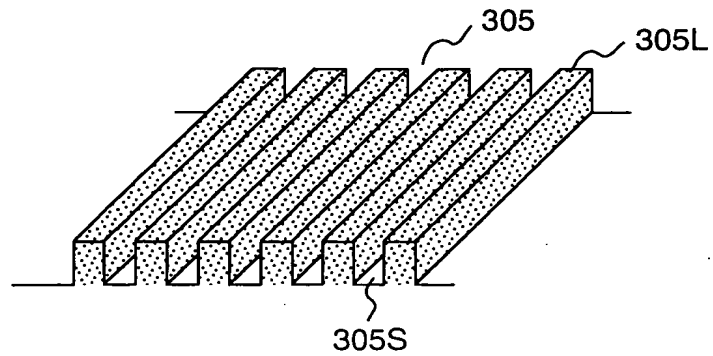
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**FIG. 5A****FIG. 5B****FIG. 6**

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FIG. 7

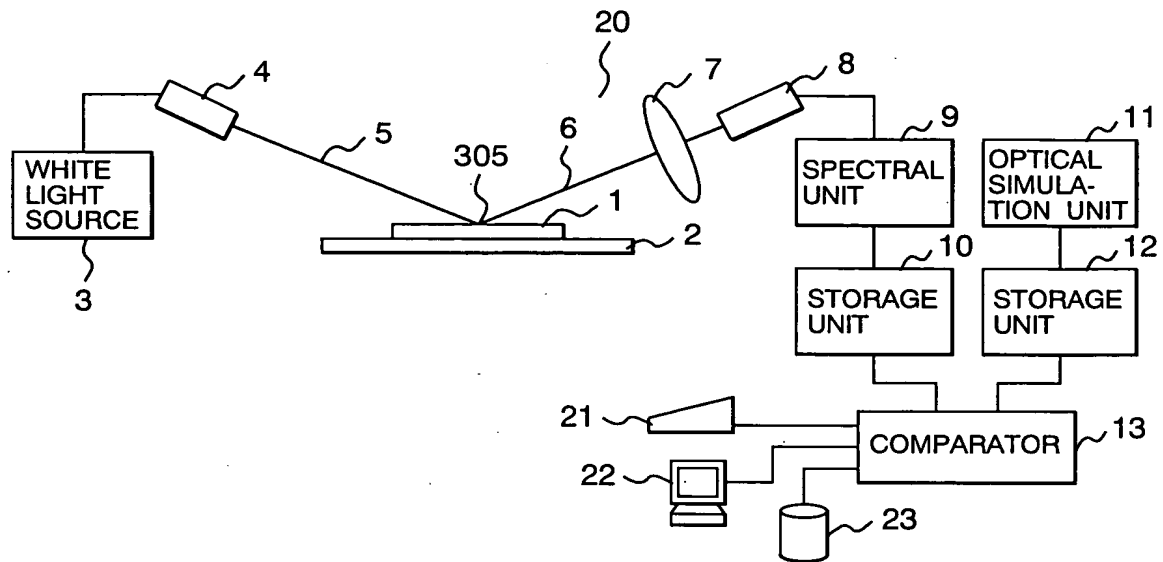
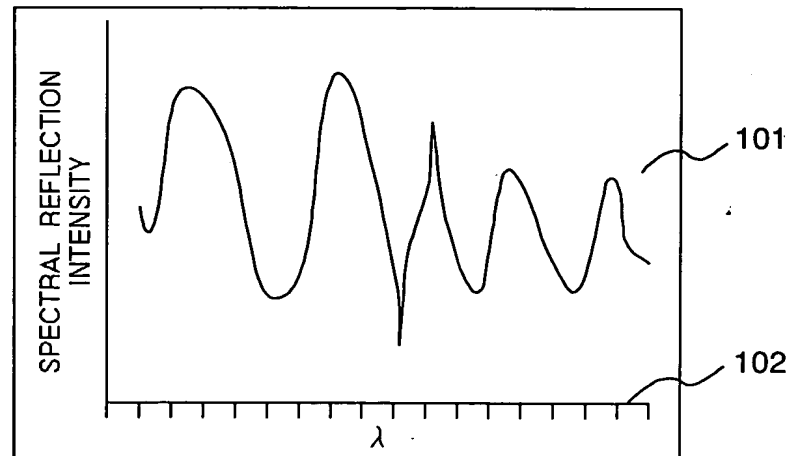


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FIG. 9

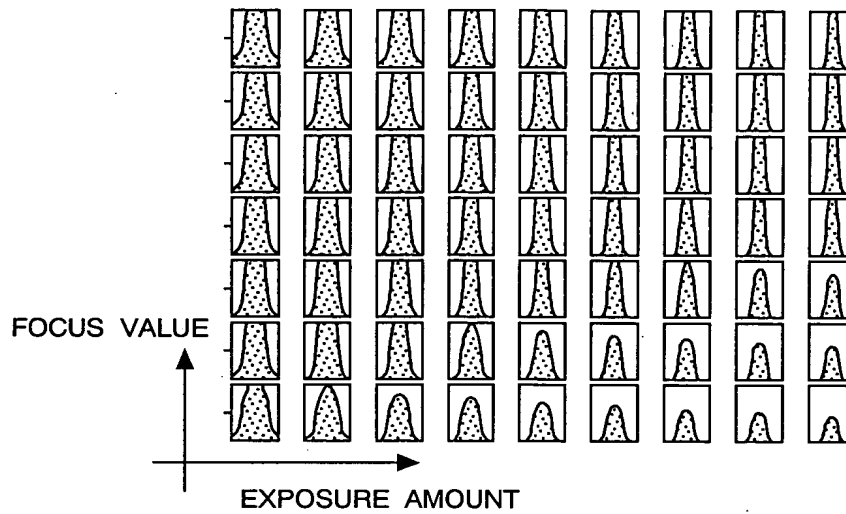


FIG. 10A

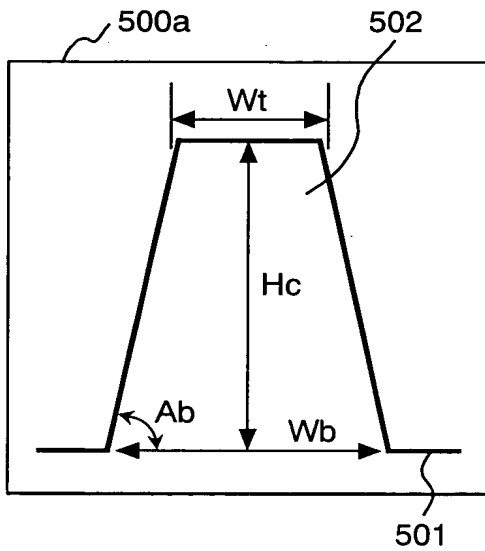
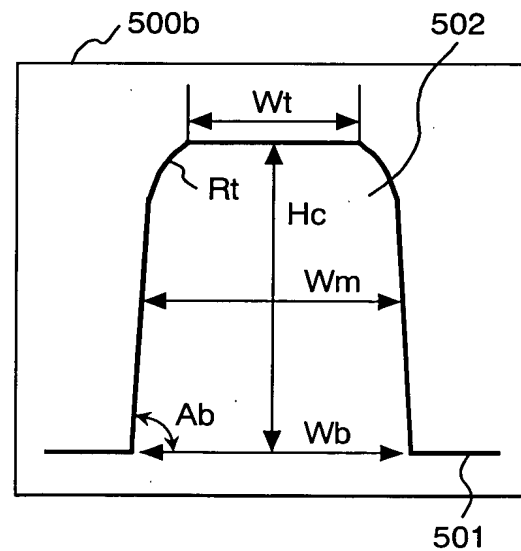


FIG. 10B



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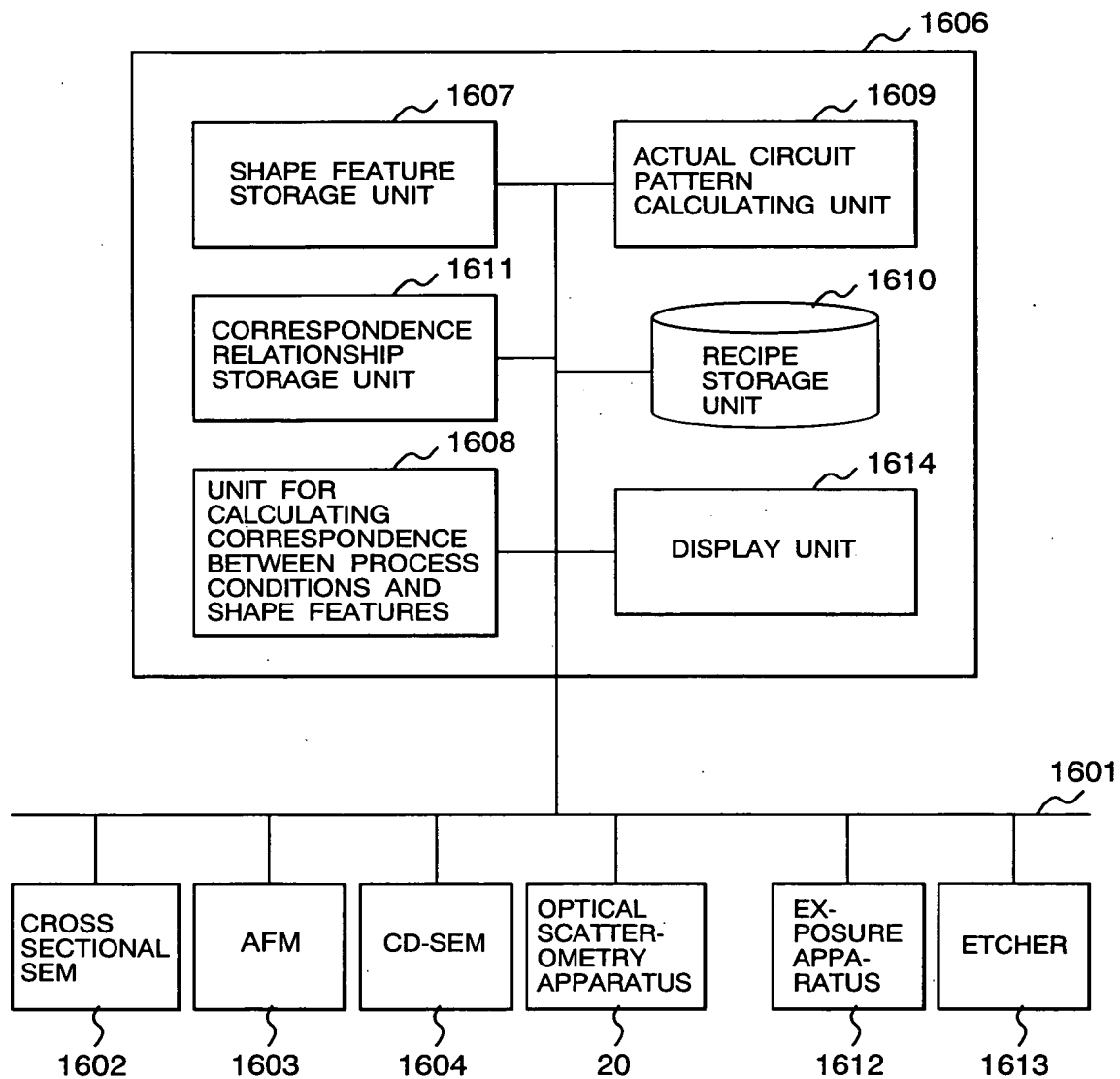
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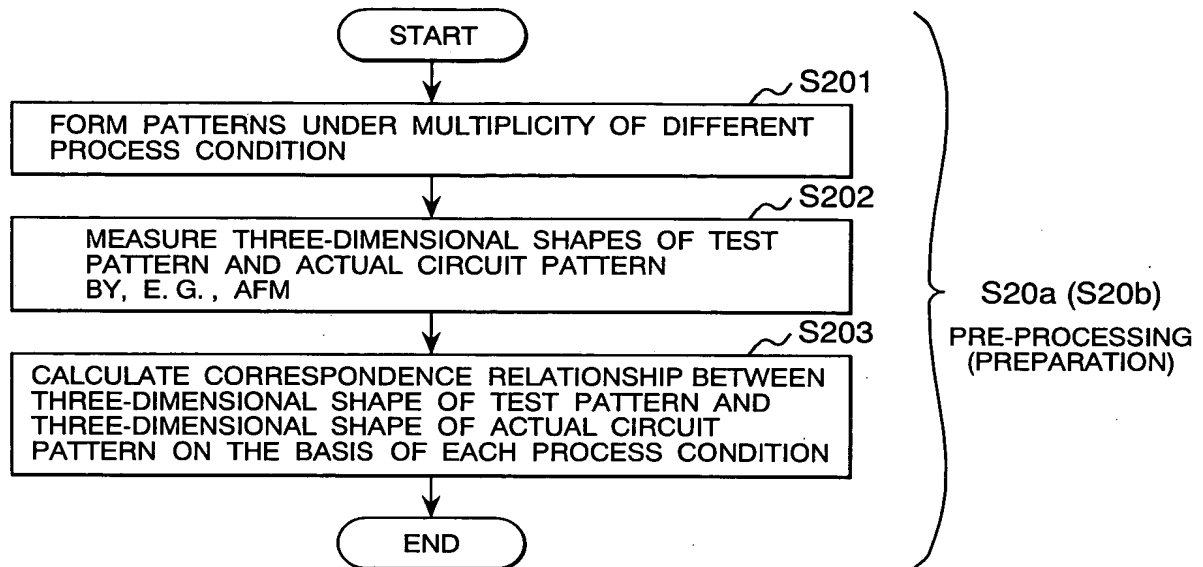
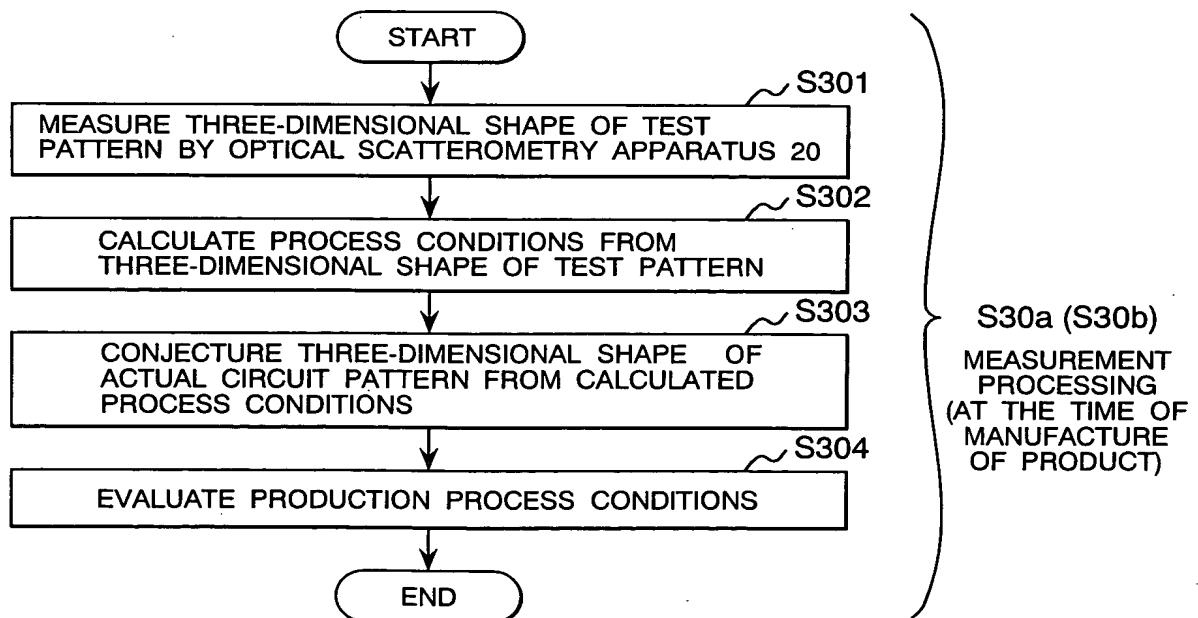
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FIG. 11





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**FIG. 12A****FIG. 12B**

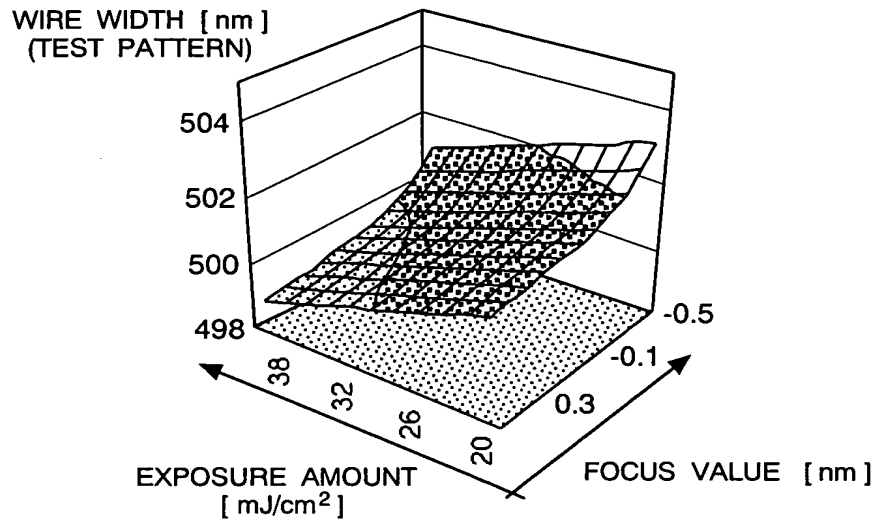
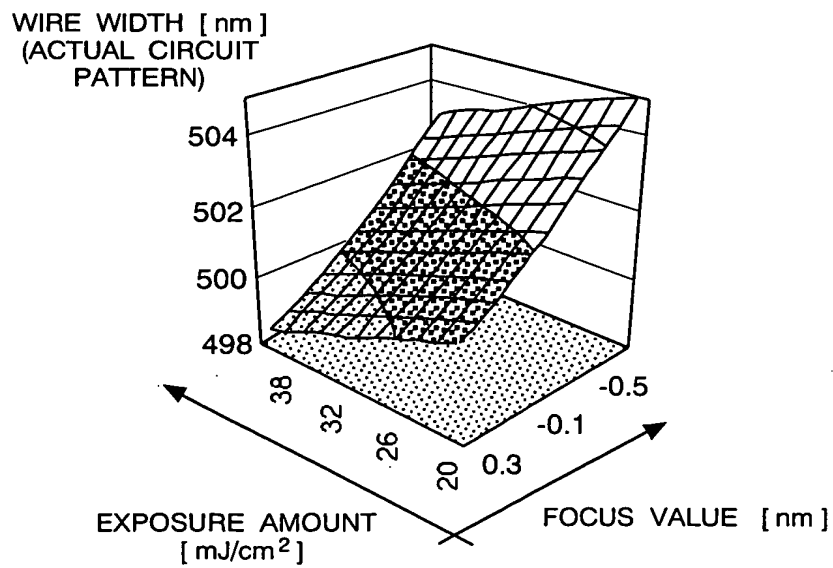
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**FIG. 13A****FIG. 13B**

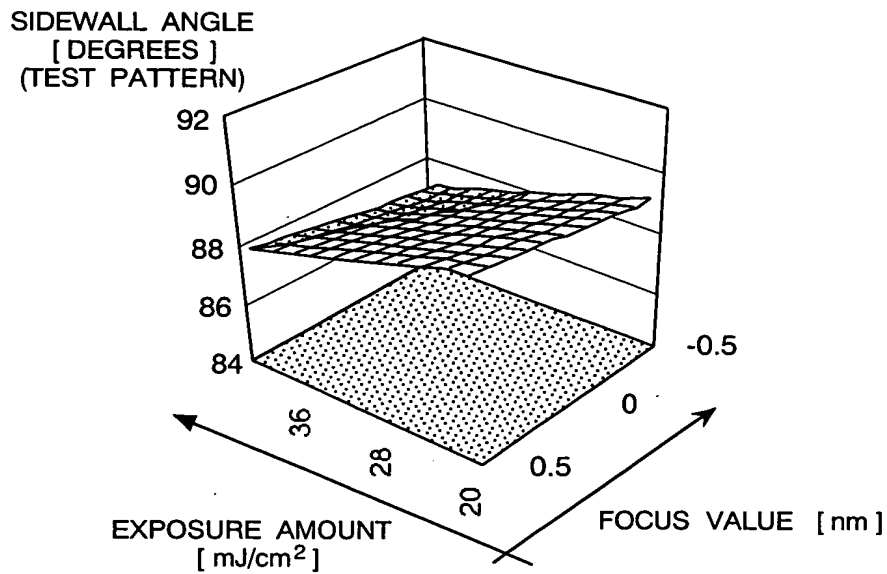
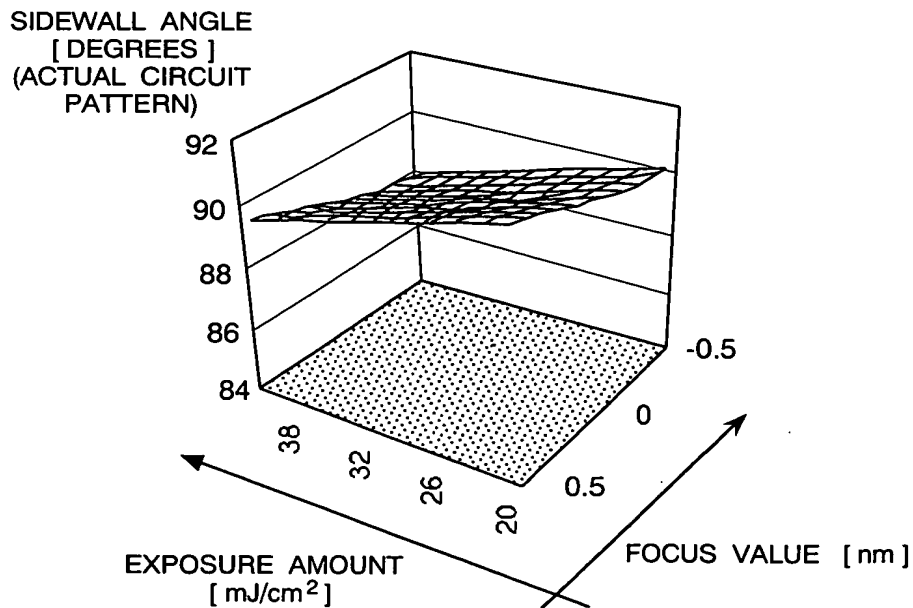
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**FIG. 14A****FIG. 14B**

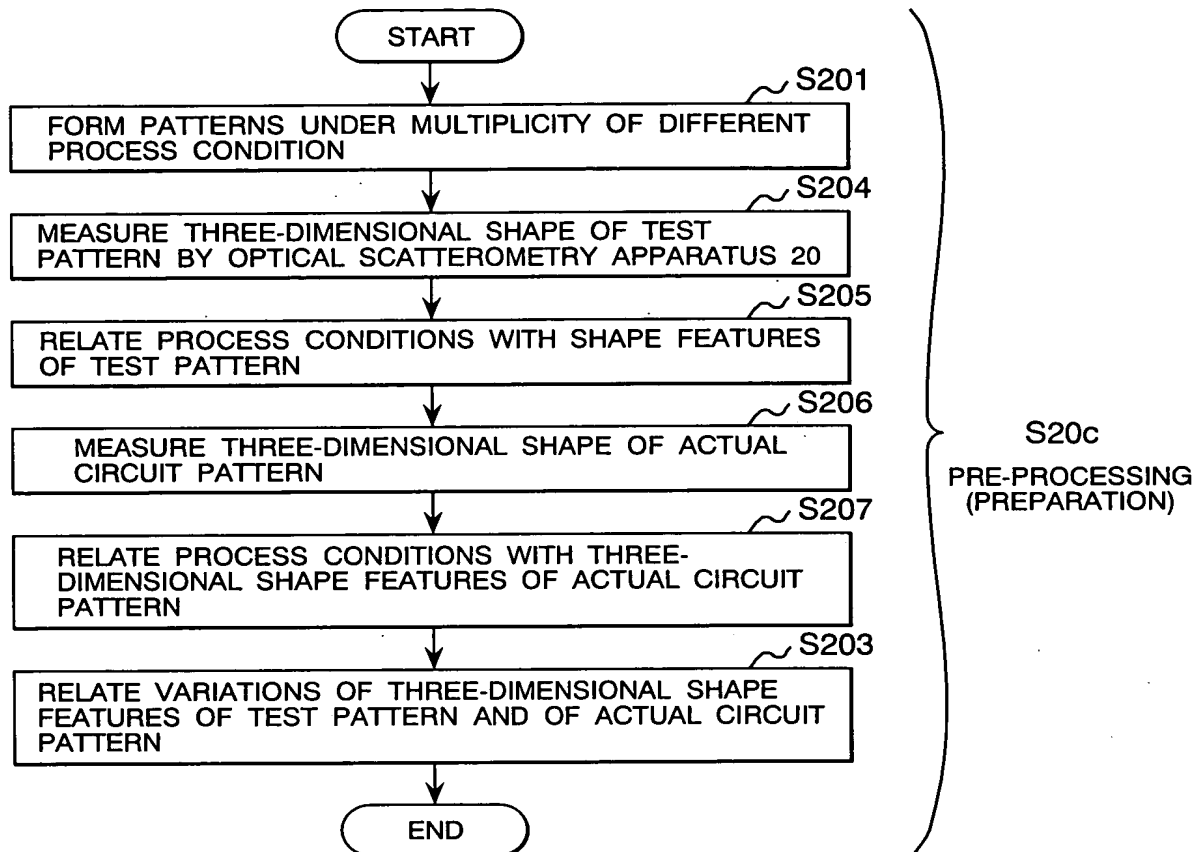
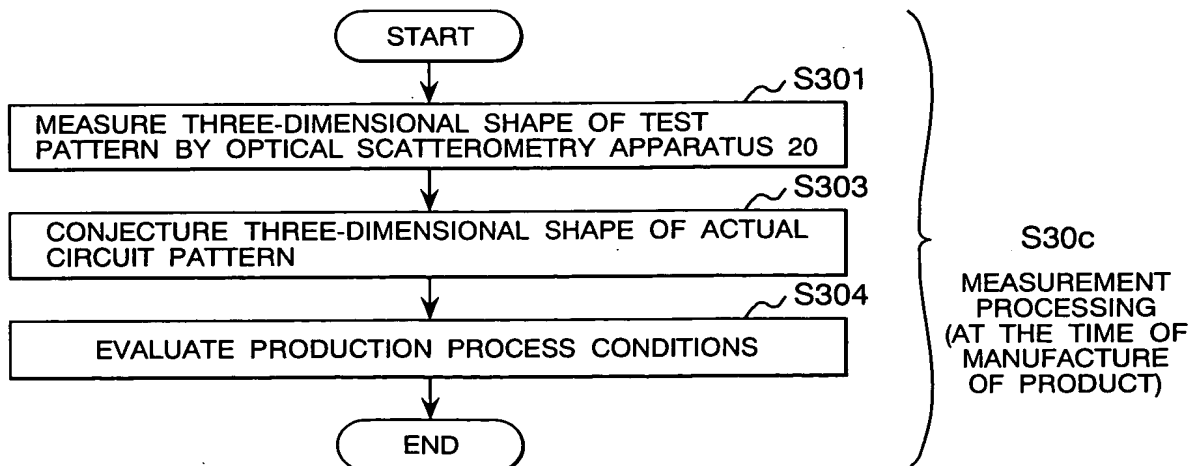
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**FIG. 15A****FIG. 15B**

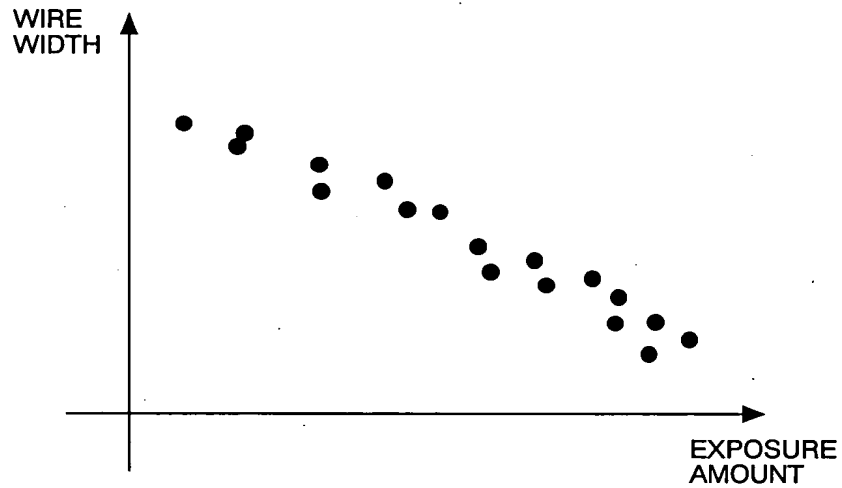
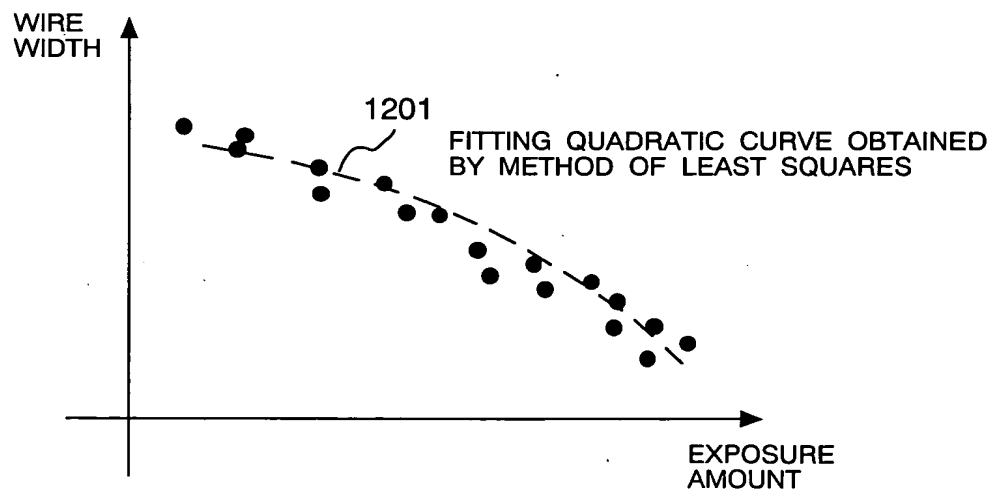
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**FIG. 16****FIG. 17**

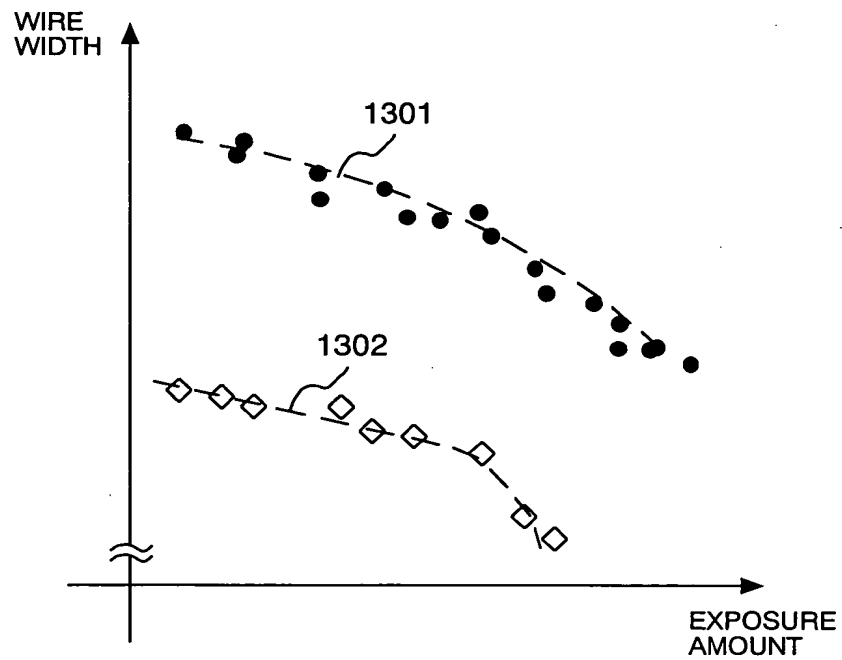
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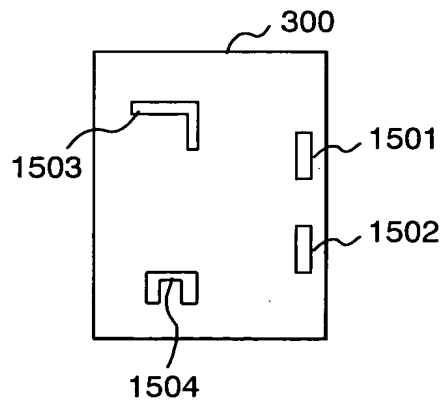
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**FIG. 18**

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**FIG. 19**

#	TEST PATTERN	CRITICAL ACTUAL CIRCUIT PATTERN
1	PATTERN A WIRE WIDTH = F1a (CONDITION1, CONDITION2) SIDEWALL ANGLE = F2a (CONDITION1, CONDITION2) .....	PATTERN C WIRE WIDTH = F1c (CONDITION1, CONDITION2) SIDEWALL ANGLE = F2c (CONDITION1, CONDITION2) .....
2	PATTERN B WIRE WIDTH = F1b (CONDITION1, CONDITION2) SIDEWALL ANGLE = F2b (CONDITION1, CONDITION2) .....	PATTERN D WIRE WIDTH = F1d (CONDITION1, CONDITION2) SIDEWALL ANGLE = F2d (CONDITION1, CONDITION2) .....

**FIG. 20**

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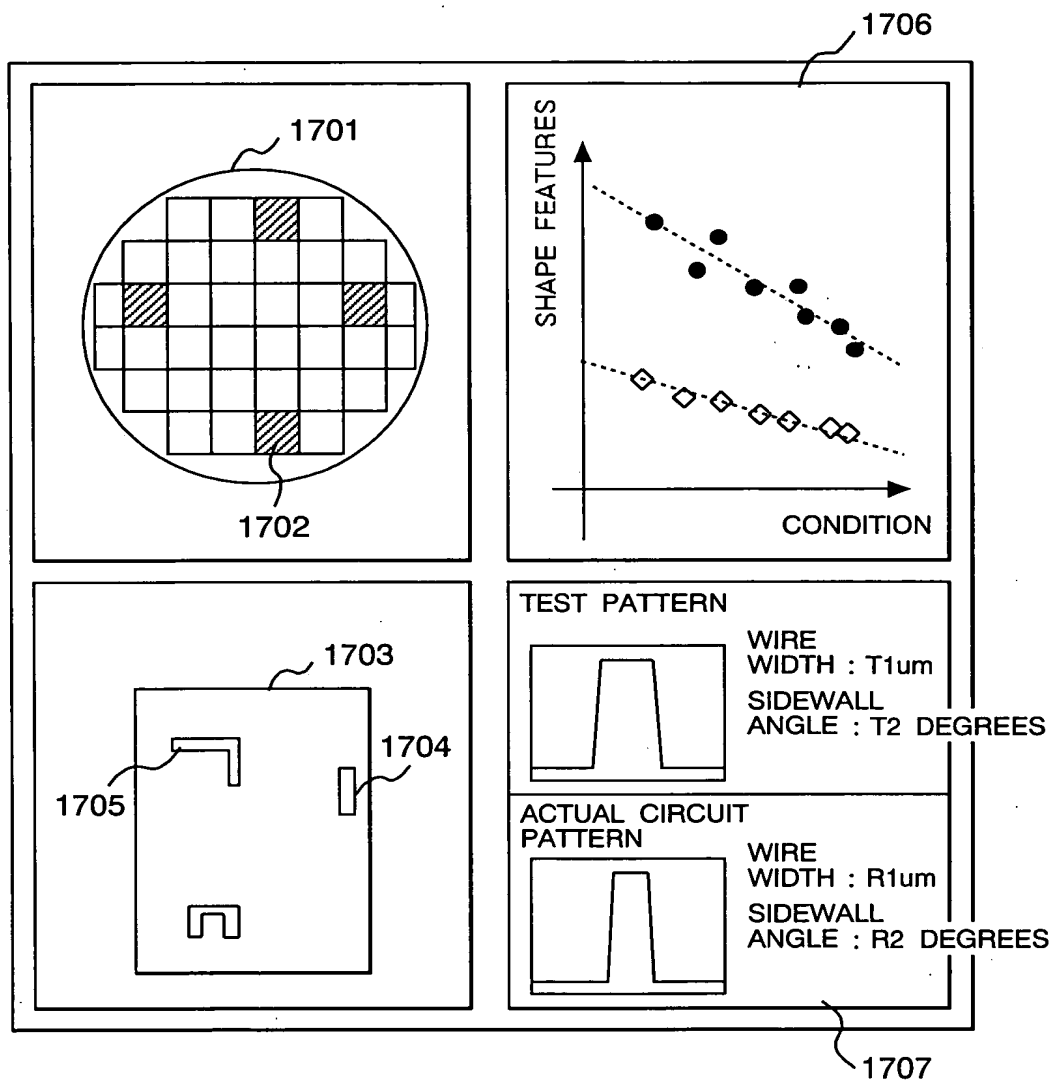
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FIG. 21





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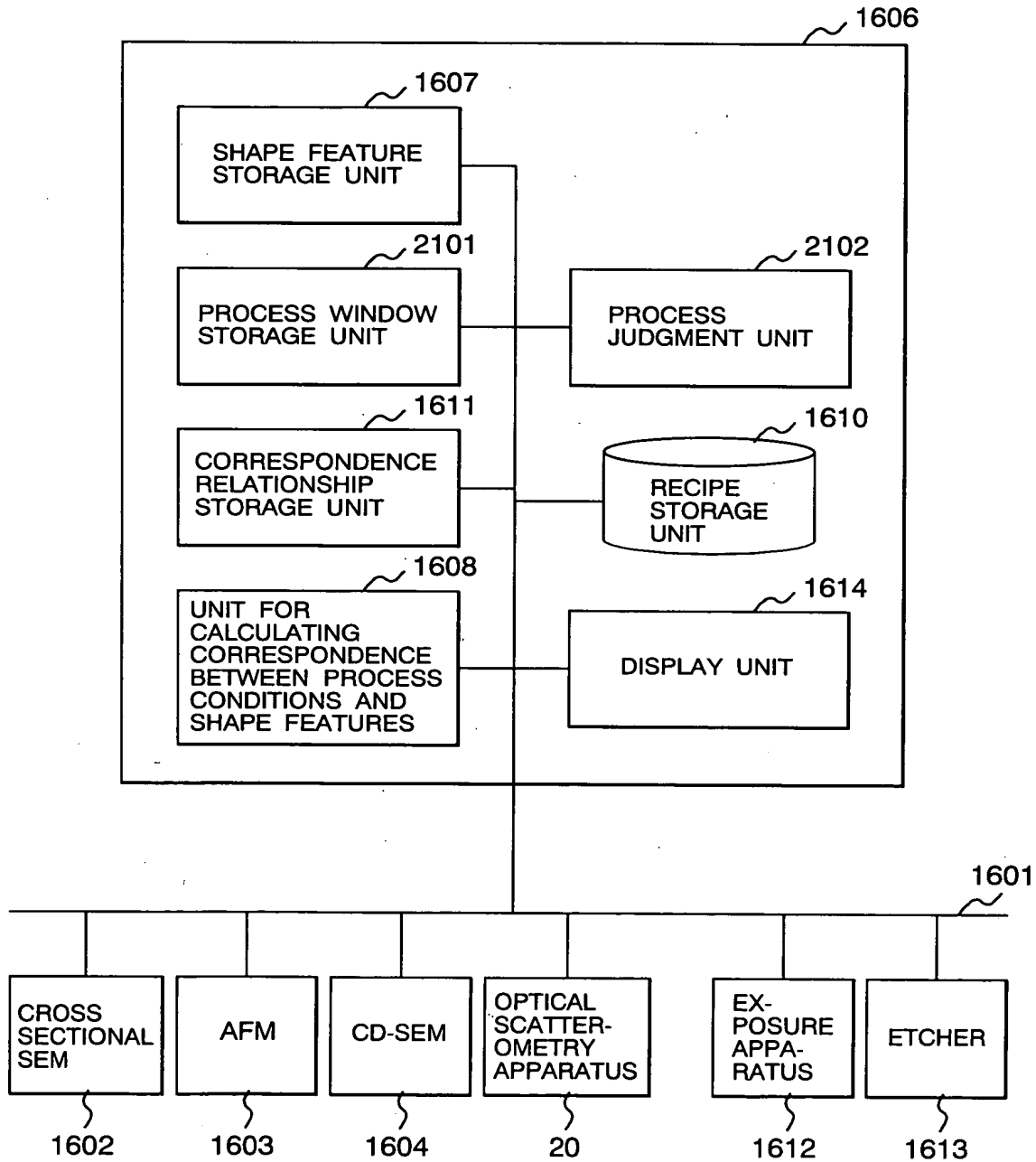
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FIG. 22



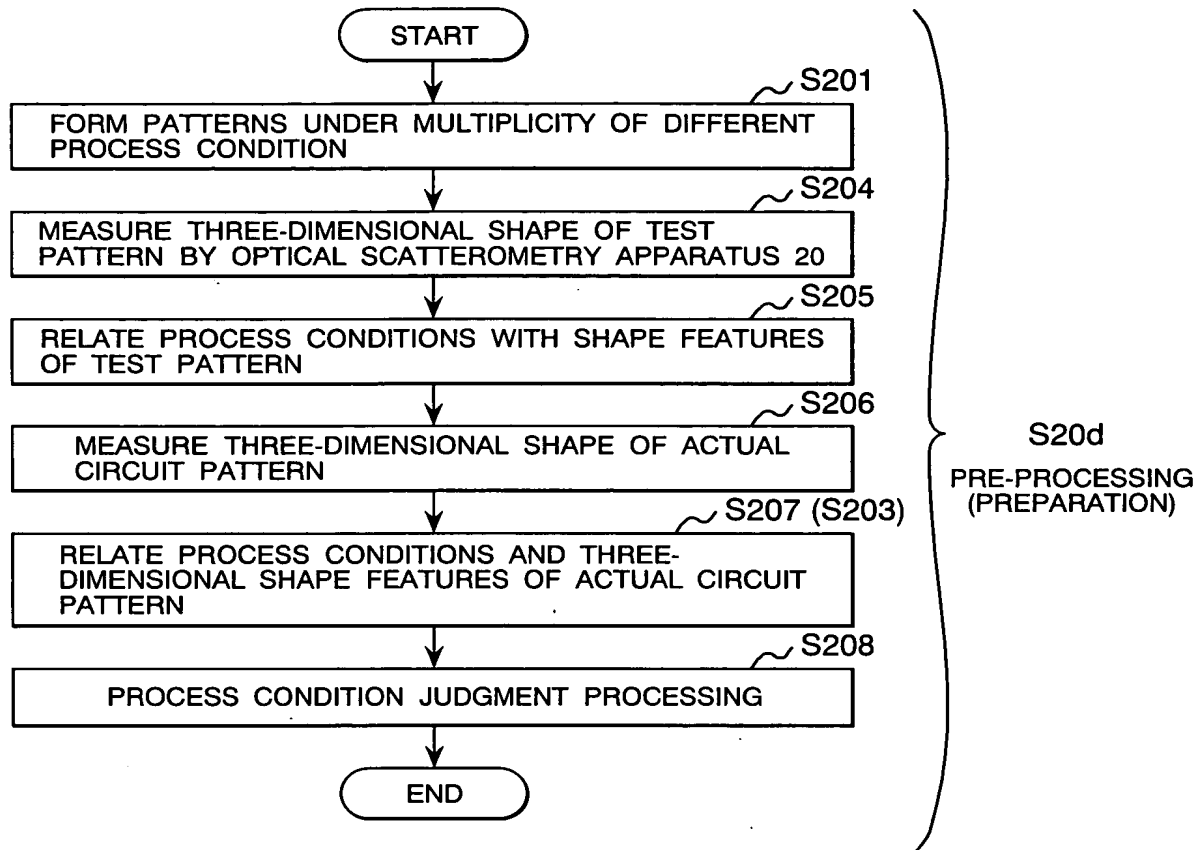
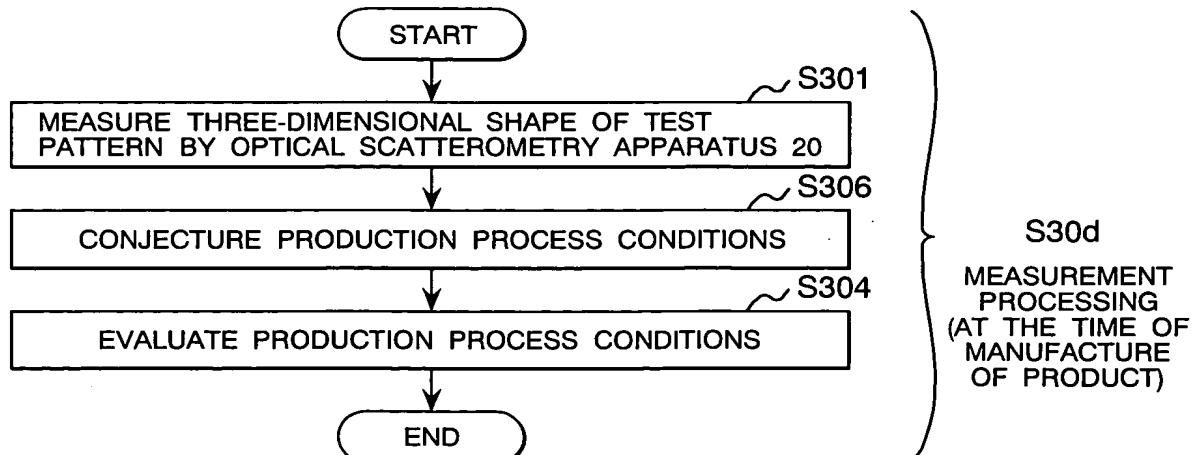
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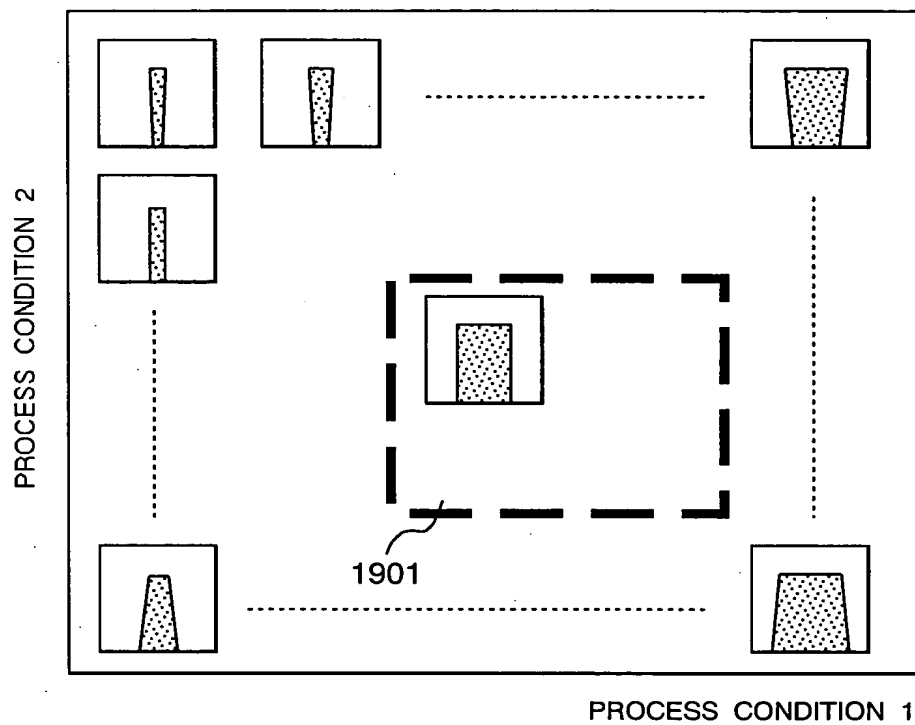
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**FIG. 23A****FIG. 23B**

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**FIG. 24**

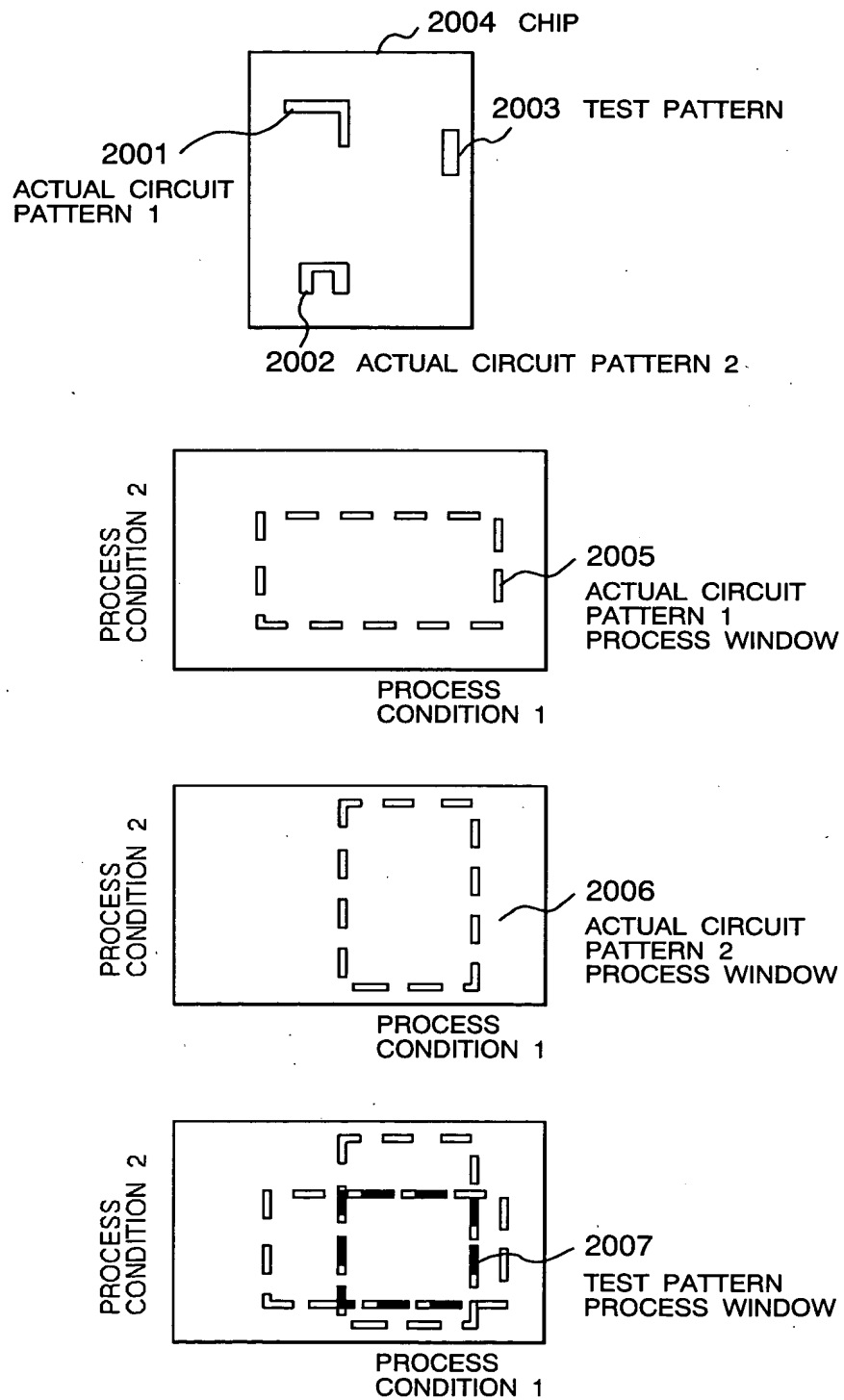
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**FIG. 25**

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FIG. 26

